

PROCEEDINGS OF SPIE

*10th International Symposium on Advanced
Optical Manufacturing and Testing Technologies*

Advanced and Extreme Micro- Nano Manufacturing Technologies

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14–17 June 2021
Chengdu, China

Organized by
IOE – Institute of Optics and Electronics, Chinese Academy of Sciences (China)

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Supported by
Ministry of Science and Technology of China (China) • Chinese Academy of Sciences (China) • National Natural Science Foundation of China (China)

Published by
SPIE

Volume 12073

Proceedings of SPIE 0277-786X, V. 12073

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Please use the following format to cite material from these proceedings:

Author(s), "Title of Paper," in *10th International Symposium on Advanced Optical Manufacturing and Testing Technologies: Advanced and Extreme Micro-Nano Manufacturing Technologies*, edited by Xiong Li, Xuan-Ming Duan, Mingbo Pu, Changtao Wang, Song Hu, Xiangang Luo, Proc. of SPIE 12073, Seven-digit Article CID Number (DD/MM/YYYY); (DOI URL).

ISSN: 0277-786X

ISSN: 1996-756X (electronic)

ISBN: 9781510650213

ISBN: 9781510650220 (electronic)

Published by

SPIE

P.O. Box 10, Bellingham, Washington 98227-0010 USA

Telephone +1 360 676 3290 (Pacific Time)

SPIE.org

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